



SLOVENSKI STANDARD
oSIST prEN IEC 60749-26:2025
01-januar-2025

**Polprevodniški elementi - Metode za mehansko in klimatsko preskušanje - 26. del:
Preskušanje občutljivosti na elektrostatično razelektritev (ESD) - Model
človeškega telesa (HBM)**

Semiconductor devices - Mechanical and climatic test methods - Part 26: Electrostatic discharge (ESD) sensitivity testing - Human body model (HBM)

Halbleiterbauelemente - Mechanische und klimatische Prüfverfahren - Teil 26: Prüfung der Empfindlichkeit gegen elektrostatische Entladungen (ESD) - Human Body Model (HBM)

Dispositifs à semiconducteurs - Méthodes d'essais mécaniques et climatiques - Partie 26: Essai de sensibilité aux décharges électrostatiques (DES) - Modèle du corps humain (HBM)

<https://standards.iteh.ai>

<https://standards.iteh.ai/catalog/standards/sist/787de785-9b87-4f1a-b2dd-d3b61f47e4ad/osist-pren-iec-60749-26-2025>

Ta slovenski standard je istoveten z: prEN IEC 60749-26:2024

ICS:

31.080.01	Polprevodniški elementi (naprave) na splošno	Semiconductor devices in general
-----------	---	-------------------------------------

oSIST prEN IEC 60749-26:2025	en
-------------------------------------	-----------



47/2882/CDV

COMMITTEE DRAFT FOR VOTE (CDV)

PROJECT NUMBER: IEC 60749-26 ED5	
DATE OF CIRCULATION: 2024-11-29	CLOSING DATE FOR VOTING: 2025-02-21
SUPERSEDES DOCUMENTS: 47/2872/RR	

IEC TC 47 : SEMICONDUCTOR DEVICES	
SECRETARIAT: Korea, Republic of	SECRETARY: Mr Cheolung Cha
OF INTEREST TO THE FOLLOWING COMMITTEES:	HORIZONTAL FUNCTION(S):
ASPECTS CONCERNED:	
<input checked="" type="checkbox"/> SUBMITTED FOR CENELEC PARALLEL VOTING Attention IEC-CENELEC parallel voting The attention of IEC National Committees, members of CENELEC, is drawn to the fact that this Committee Draft for Vote (CDV) is submitted for parallel voting. The CENELEC members are invited to vote through the CENELEC online voting system.	<input type="checkbox"/> NOT SUBMITTED FOR CENELEC PARALLEL VOTING

This document is still under study and subject to change. It should not be used for reference purposes.

Recipients of this document are invited to submit, with their comments, notification of any relevant patent rights of which they are aware and to provide supporting documentation.

Recipients of this document are invited to submit, with their comments, notification of any relevant "In Some Countries" clauses to be included should this proposal proceed. Recipients are reminded that the CDV stage is the final stage for submitting ISC clauses. (SEE AC/22/2007 OR NEW GUIDANCE DOC).

TITLE:

Semiconductor devices - Mechanical and climatic test methods - Part 26: Electrostatic discharge (ESD) sensitivity testing - Human body model (HBM)

PROPOSED STABILITY DATE: 2029

NOTE FROM TC/SC OFFICERS:

1	CONTENTS	
2	FOREWORD	5
3	1. Scope	7
4	2. Normative references	7
5	3. Terms and definitions	7
6	4. Apparatus and required equipment	11
7	4.1. Waveform verification equipment	11
8	4.2. Oscilloscope	11
9	4.3. Additional requirements for digital oscilloscopes	12
10	4.4. Current probe	12
11	4.5. Evaluation loads	12
12	4.6. Attenuator	12
13	4.7. Human body model simulator	12
14	4.8. HBM test equipment parasitic properties	13
15	5. Stress test equipment qualification and routine verification	13
16	5.1. Overview of required HBM tester evaluations	13
17	5.2. Measurement procedures	14
18	5.2.1. Reference pin pair determination	14
19	5.2.2. Waveform capture with current probe	14
20	5.2.3. Determination of waveform parameters	15
21	5.2.4. High voltage discharge path test	18
22	5.3. HBM tester qualification	18
23	5.3.1. HBM ESD tester qualification requirements	18
24	5.3.2. HBM tester qualification procedure	18
25	5.4. Test fixture board qualification for socketed testers	19
26	5.5. Routine waveform check requirements	20
27	5.5.1. Standard routine waveform check description	20
28	5.5.2. Waveform check frequency	20
29	5.5.3. Alternate routine waveform capture procedure	21
30	5.6. High voltage discharge path check	21
31	5.6.1. Relay testers	21
32	5.6.2. Non-relay testers	21
33	5.7. Tester waveform records	21
34	5.7.1. Tester and test fixture board qualification records	21
35	5.7.2. Periodic waveform check records	21
36	5.8. Safety	22
37	5.8.1. Initial set-up	22
38	5.8.2. Training	22
39	5.8.3. Personnel safety	22
40	6. Classification procedure	22
41	6.1. Devices for classification	22
42	6.2. Parametric and functional testing	22
43	6.3. Device stressing	22
44	6.3.1. Device stressing methods	22
45	6.3.2. No connect pins	23
46	6.4. Pin combination stressing	23
47	6.4.1. Pin combination stressing options	23

48	6.4.2.	'No-Connect' Pins	24
49	6.4.3.	Supply pins	24
50	6.4.4.	Non-supply pins	25
51	6.5.	Pin groupings	25
52	6.5.1.	Supply pin groups	25
53	6.6.	Pin stress combinations	26
54	6.6.1.	Pin stress combination categorization	26
55	6.6.2.	Non-supply and supply to supply combinations (1, 2, ... N)	28
56	6.6.3.	Non-supply to non-supply combinations	29
57	6.7.	Pin-pair stressing	29
58	6.8.	Low-Parasitic HBM Simulator Allowance	29
59	6.9.	Testing after stressing	30
60	7.	Failure criteria	30
61	8.	Component classification	30
62	Annex A (informative)	Cloned non-supply (I/O) pin sampling test method	31
63	A.1	Purpose and overview	31
64	A.2	Pin sampling overview and statistical details	31
65	A.3	IC product selections	32
66	A.4	Randomly selecting and testing cloned I/O pins	33
67	A.5	Determining if sampling can be used with the supplied Excel spreadsheet	33
68	A.5.1	Using the supplied Excel spreadsheet	33
69	A.5.2	Without using the Excel spreadsheet	33
70	A.6	HBM testing with a sample of cloned I/O pins	34
71	A.7	Examples of testing with sampled cloned I/Os	34
72	Annex B (informative)	Determination of withstand thresholds for pin or pin-combination subsets	37
73	B.1	Introduction	37
74	B.2	Testing procedures	37
75	B.3	Restrictions	38
76	B.4	Example of using subset withstand threshold data	38
77	Annex C (informative)	HBM test equipment parasitic properties	39
78	C.1	Optional trailing pulse detection equipment / apparatus	39
79	C.2	Optional pre-pulse voltage rise detection test equipment	40
80	C.3	Optional Pre-HBM Current Spike Detection Equipment	42
81	C.4	Open-relay tester capacitance parasitics	43
82	C.5	Test to determine if an HBM simulator is a low-parasitic simulator	44
83	Annex D (informative)	HBM test method flow chart	46
84	Annex E (informative)	Failure window detection testing methods	49
85	E.1	Methodology	49
86	E.2	Combined Withstand Threshold Method and Window Search	49
87	E.3	Failure Window Detection with a Known Withstand Threshold	49
88	Bibliography	51
89			
90			
91	Figure 1 – Simplified HBM simulator circuit with loads		13
92	Figure 2 – Current waveform through shorting wires		16

93	Figure 3 – Current waveform through a 500 Ω resistor	17
94	Figure 4 – Peak current short circuit ringing waveform	18
95	Figure A.1 – SPL, V1, VM, and z with the Bell shape distribution pin failure curve	32
96	Figure A.2 – I/O sampling test method flow chart	36
97	Figure C.1 – Diagram of trailing pulse measurement setup	39
98	Figure C.2 – Positive stress at 4 000 V	40
99	Figure C.3 – Negative stress at 4 000 V	40
100	Figure C.4 – Illustration of measuring voltage before HBM pulse with a Zener diode or	
101	a device	41
102	Figure C.5 – Example of voltage rise before the HBM current pulse across a 9,4 V	
103	Zener diode	41
104	Figure C.6 – Optional Pre-Current Pulse Detection Equipment/Apparatus	42
105	Figure C.7 – Positive Stress at 1000 V	43
106	Figure C.8 – Diagram of a 10-pin shorting test device showing current probe	45
107	Figure D.1 – HBM test method flow chart (1 of 3, HBM Classification Procedure)	46
108		
109	Table 1 – Waveform specification	20
110	Table 2 – Preferred pin combinations sets	27
111	Table 3 – Alternative pin combinations sets	27
112	Table 4 – HBM ESD component classification levels	30
113	Table.B.1. Inclusion of Lower ESD Level High-Speed Pin Data ESD Information for	
114	Handling of ESDS in an ESD Protected Area (Required)	38
115		
116		

117 INTERNATIONAL ELECTROTECHNICAL COMMISSION

118

119

120

121

122

123

124

125

126

SEMICONDUCTOR DEVICES –
MECHANICAL AND CLIMATIC TEST METHODS –

**Part 26: Electrostatic discharge (ESD) sensitivity testing –
Human body model (HBM)**

FOREWORD

127 1) The International Electrotechnical Commission (IEC) is a worldwide organization for standardization comprising
128 all national electrotechnical committees (IEC National Committees). The object of IEC is to promote international
129 co-operation on all questions concerning standardization in the electrical and electronic fields. To this end and
130 in addition to other activities, IEC publishes International Standards, Technical Specifications, Technical Reports,
131 Publicly Available Specifications (PAS) and Guides (hereafter referred to as “IEC Publication(s)”). Their
132 preparation is entrusted to technical committees; any IEC National Committee interested in the subject dealt with
133 may participate in this preparatory work. International, governmental and non-governmental organizations liaising
134 with the IEC also participate in this preparation. IEC collaborates closely with the International Organization for
135 Standardization (ISO) in accordance with conditions determined by agreement between the two organizations.

136 2) The formal decisions or agreements of IEC on technical matters express, as nearly as possible, an international
137 consensus of opinion on the relevant subjects since each technical committee has representation from all
138 interested IEC National Committees.

139 3) IEC Publications have the form of recommendations for international use and are accepted by IEC National
140 Committees in that sense. While all reasonable efforts are made to ensure that the technical content of IEC
141 Publications is accurate, IEC cannot be held responsible for the way in which they are used or for any
142 misinterpretation by any end user.

143 4) In order to promote international uniformity, IEC National Committees undertake to apply IEC Publications
144 transparently to the maximum extent possible in their national and regional publications. Any divergence between
145 any IEC Publication and the corresponding national or regional publication shall be clearly indicated in the latter.

146 5) IEC itself does not provide any attestation of conformity. Independent certification bodies provide conformity
147 assessment services and, in some areas, access to IEC marks of conformity. IEC is not responsible for any
148 services carried out by independent certification bodies.

149 6) All users should ensure that they have the latest edition of this publication.

150 7) No liability shall attach to IEC or its directors, employees, servants or agents including individual experts and
151 members of its technical committees and IEC National Committees for any personal injury, property damage or
152 other damage of any nature whatsoever, whether direct or indirect, or for costs (including legal fees) and
153 expenses arising out of the publication, use of, or reliance upon, this IEC Publication or any other IEC Publications.

154 8) Attention is drawn to the Normative references cited in this publication. Use of the referenced publications is
155 indispensable for the correct application of this publication.

156 9) Attention is drawn to the possibility that some of the elements of this IEC Publication may be the subject of patent
157 rights. IEC shall not be held responsible for identifying any or all such patent rights.

158 International Standard IEC 60749-26 has been prepared by IEC technical committee 47:
159 Semiconductor devices in collaboration with technical committee 101: Electrostatics.

160 This fifth edition cancels and replaces the fourth edition published in 2018. This edition
161 constitutes a technical revision. This standard is based upon ANSI/ESDA/JEDEC JS-001-2023.
162 It is used with permission of the copyright holders, ESD Association and JEDEC Solid state
163 Technology Association.

164 This edition includes the following significant technical changes with respect to the previous
165 edition:

166 a) new definitions have been added

167 b) text has been added to clarify the designation of and allowances resulting from “low
168 parasitics”. The new designation includes the maximum number of pins of a device that can
169 pass the test procedure.

170

171 The text of this International Standard is based on the following documents:

FDIS	Report on voting
47/xxxx/FDIS	47/yyyy/RVD

172

173 Full information on the voting for the approval of this International Standard can be found in the
174 report on voting indicated in the above table.

175 The language used for the development of this International Standard is English.

176 This document has been drafted in accordance with the ISO/IEC Directives, Part 2, and
177 developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC
178 Supplement, available at www.iec.ch/members_experts/refdocs. The main document types
179 developed by IEC are described in greater detail at www.iec.ch/publications.

180

181 A list of all parts in the IEC 60749 series, published under the general title *Semiconductor*
182 *devices – Mechanical and climatic test methods*, can be found on the IEC website.

183 The committee has decided that the contents of this document will remain unchanged until the
184 stability date indicated on the IEC website under "<http://webstore.iec.ch>" in the data related to
185 the specific document. At this date, the document will be

- 186 • reconfirmed,
- 187 • withdrawn,
- 188 • replaced by a revised edition, or
- 189 • amended.

[oSIST prEN IEC 60749-26:2025](https://standards.iteh.ai/catalog/standards/sist/787de785-9b87-4f1a-b2dd-d3b61f47e4ad/osist-pren-iec-60749-26-2025)

<https://standards.iteh.ai/catalog/standards/sist/787de785-9b87-4f1a-b2dd-d3b61f47e4ad/osist-pren-iec-60749-26-2025>

IMPORTANT – The 'colour inside' logo on the cover page of this publication indicates that it contains colours which are considered to be useful for the correct understanding of its contents. Users should therefore print this document using a colour printer.

191

192

SEMICONDUCTOR DEVICES – MECHANICAL AND CLIMATIC TEST METHODS –

Part 26: Electrostatic discharge (ESD) sensitivity testing – Human body model (HBM)

193
194
195
196
197
198
199
200

201 1. Scope

202 This part of IEC 60749 establishes the procedure for testing, evaluating, and classifying
203 components and microcircuits according to their susceptibility (sensitivity) to damage or
204 degradation by exposure to a defined human body model (HBM) electrostatic discharge (ESD).

205 The purpose of this document is to establish a test method that will replicate HBM failures and
206 provide reliable, repeatable HBM ESD test results from tester to tester, regardless of component
207 type. Repeatable data will allow accurate classifications and comparisons of HBM ESD
208 sensitivity levels.

209 ESD testing of semiconductor devices is selected from this test method, the machine model
210 (MM) test method (see IEC 60749-27) or other ESD test methods in the IEC 60749 series.
211 Unless otherwise specified, this test method is the one selected.

212 2. Normative references

213 The following documents are referred to in the text in such a way that some or all of their content
214 constitutes requirements of this document. For dated references, only the edition cited applies.
215 For undated references, the latest edition of the referenced document (including any
216 amendments) applies.

217 IEC 60749-28, *Semiconductor devices – Mechanical and climatic test methods – Part 28:*
218 *Electrostatic discharge (ESD) sensitivity testing – Machine model (MM)*

219 3. Terms and definitions

220 For the purposes of this document, the following terms and definitions apply.

221 ISO and IEC maintain terminological databases for use in standardization at the following
222 addresses:

- 223 • IEC Electropedia: available at <http://www.electropedia.org/>
- 224 • ISO Online browsing platform: available at <http://www.iso.org/obp>

225 3.1. 226 above-passivation layer 227 APL

228 A low-impedance metal plane built on the surface of a die, above the passivation layer, which
229 connects a group of bumps or pins (typically power or ground).
230

231 Note 1 to entry This structure is sometimes referred to as a redistribution layer (RDL). There may be multiple APLs
232 (sometimes referred to as Islands) for a power or ground group.
233
234

235

236 **3.2.**
 237 **associated non-supply pin**
 238 non-supply pin (typically an I/O pin) associated with a supply pin group

239 Note 1 to entry A non-supply pin is considered to be associated with a supply pin group if either:

- 240 a) the current from the supply pin group (i.e., VDDIO) is required for the function of the electrical circuit(s)
 241 (I/O driver) that connect(s) (high/low impedance) to that non-supply pin;
- 242 b) a parasitic path exists between non-supply and supply pin group (e.g., open-drain type non-supply pin to a VCC
 243 supply pin group that connects to a nearby N-well guard ring).

244 **3.3.**
 245 **cloned non-supply (I/O) pin**
 246 set of input, output or bidirectional pins using the same I/O cell and electrical schematic and
 247 sharing the same associated supply pin group(s) including ESD power clamp(s)

248 **3.4.**
 249 **component**
 250 item such as a resistor, diode, transistor, integrated circuit or hybrid circuit

251 **3.5.**
 252 **component failure**
 253 condition in which a tested component does not meet one or more specified static or dynamic
 254 data sheet parameters

255 **3.6.**
 256 **coupled non-supply pin pair**
 257 two pins that have an intended direct current path (such as a pass gate or resistors, such as
 258 differential amplifier inputs, or low voltage differential signalling (LVDS) pins), including
 259 analogue and digital differential pairs and other special function pairs (e.g., D+/D-,
 260 XTALin/XTALout, RFin/RFout, TxP/TxN, RxP/RxN, CCP_DP/CCN_DN, etc.)

261 **3.7.**
 262 **data sheet parameters**
 263 static and dynamic component performance data supplied by the component manufacturer or
 264 supplier

265 **3.8.**
 266 **exposed pad**
 267 exposed metal plate on an IC package, connected to the silicon substrate and acting as a heat
 268 sink. This metal plate may or may not be electrically connected to the die. The exposed pad
 269 may be categorized as either supply, non-supply or no-connect

270 **3.9.**

271 **3.10.**
 272 **feedthrough**
 273 direct or indirect (via a series resistor) connection from a pad cell layout. This connection may
 274 allow additional elements, not included in the pad cell, to make electrical connections to the
 275 bond pad (see Annex A). This is not to be confused with the term feed-through used in Clause
 276 5 which refers to test boards.

277 **3.11.**
 278 **failure window**
 279 intermediate range of stress voltages that can induce failure in a particular device type, when
 280 the device type can pass some stress voltages both higher and lower than this range

281 Note 1 to entry: A component with a failure window can pass a 500 V test, fail a 1 000 V test and pass a 2 000 V
 282 test. The withstand voltage of such a device is 500 V.

283 **3.12.**
 284 **human body model electrostatic discharge**
 285 **HBM ESD**
 286 ESD event meeting the waveform criteria specified in this document, approximating the
 287 discharge from the fingertip of a typical human being to a grounded device

288 **3.13.**
 289 **HBM ESD tester**
 290 HBM simulator
 291 equipment that applies an HBM ESD to a component

292 **3.14.**
 293 I_{ps}
 294 peak current value determined by the current at time t_{max} on the linear extrapolation of the
 295 exponential current decay curve, based on the current waveform data over a 40 nanosecond
 296 period beginning at t_{max}

297 SEE: Figure 2 a).

298 **3.15.**
 299 I_{psmax}
 300 highest current value measured including the overshoot or ringing components due to internal
 301 test simulator RLC parasitics

302 SEE: Figure 2 a).

303 **3.16.**
 304 **no connect pin**
 305 package interconnection that is not electrically connected to a die

306 EXAMPLE: Pin, bump, ball interconnection.

307 Note 1 to entry: There are some pins which are labelled as no connect, which are actually connected to the die and
 308 should not be classified as a no connect pin.

309 **3.17.**
 310 **non-socketed tester**
 311 HBM simulator that makes contact to the device under test (DUT) pins (or balls, lands, bumps
 312 or die pads) with test probes rather than placing the DUT in a socket

313 **3.18.**
 314 **non-supply pin**
 315 pin that is not categorized as a supply pin or no connect

316 Note 1 to entry This includes pins such as input, output, offset adjusts, compensation, clocks, controls, address,
 317 data, Vref pins and VPP pins on EPROM memory. Most non-supply pins transmit or receive information such as
 318 digital or analogue signals, timing, clock signals, and voltage or current reference levels.

319 **3.19.**
 320 **package plane**
 321 low impedance metal layer built into an IC package connecting a group of bumps or pins
 322 (typically power or ground)

323 Note 1 to entry: There may be multiple package planes (sometimes referred to as islands) for each power and
 324 ground group.

325 **3.20.**
 326 **pre-pulse voltage**
 327 voltage occurring at the device under test (DUT) just prior to the generation of the HBM current
 328 pulse

329 SEE: Clause C.2.

330 **3.21.**

331 **pulse generation circuit**

332 dual polarity pulse source circuit network that produces a human body discharge current
333 waveform

334 Note 1 to entry The circuit network includes a pulse generator with its test equipment internal path up to the contact
335 pad of the test fixture. This circuit is also referred to as dual polarity pulse source.

336 **3.22.**

337 **ringing**

338 high frequency oscillation superimposed on a waveform

339 **3.23.**

340 **shorted non-supply pin**

341 any non-supply pin (typically an I/O pin) that is metallically connected (typically $< 3 \Omega$) on the
342 chip or within the package to another non-supply pin (or set of non-supply pins)

343 **3.24.**

344 **socketed tester**

345 HBM simulator that makes contact to DUT pins (or balls, lands, bumps or die pads) using a
346 DUT socket mounted on a test fixture board

347 **3.25.**

348 **specification limit**

349 **SPL**

350 HBM specification limit, or target specification level and is the value set by customer
351 requirement or internal target (See Annex A)

352 **3.26.**

353 **spurious current pulse**

354 small HBM shaped pulse that follows the main current pulse, and is typically defined as a
355 percentage of I_{psmax}

356 **3.27.**

357 **step-stress hardening**

358 ability of a component subjected to increasing ESD voltage stresses to withstand higher stress
359 levels than a similar component not previously stressed

360 EXAMPLE: A component can fail at 1 000 V if subjected to a single stress, but fail at 3 000 V if stressed
361 incrementally from 250 V.

362 **3.28.**

363 **supply pin**

364 any pin that provides current to a circuit

365 Note 1 to entry: Supply pins typically transmit no information (such as digital or analogue signals, timing, clock
366 signals, and voltage or current reference levels). For the purpose of ESD testing, power and ground pins are treated
367 as supply pins.

368 **3.29.**

369 **test fixture board**

370 specialized circuit board, with one or more component sockets, which connects the DUT(s) to
371 the HBM simulator

372 **3.30.**

373 **t_{max}**

374 time when I_{ps} is at its maximum value (I_{psmax})

375 SEE: Figure 2 a).

376 **3.31.**

377 **trailing current pulse**

378 current pulse that occurs after the HBM current pulse has decayed

379 Note 1 to entry: A trailing current pulse is a relatively constant current often lasting for hundreds of microseconds.

380 SEE: Clause C.1.

381 **3.32.**

382 **two-pin HBM tester**

383 low parasitic HBM simulator that tests DUTs in pin pairs where floating pins are not connected
384 to the simulator thereby eliminating DUT-tester interactions from parasitic tester loading of
385 floating pins

386 **3.33.**

387 **V1**

388 maximum HBM stress voltage step where all of the selected cloned non-supply pins pass (see
389 Annex A)

390 **3.34.**

391 **V2**

392 minimum HBM stress voltage step where all the selected cloned non-supply pins fail (see Annex
393 A)

394 **3.35.**

395 **VM**

396 minimum HBM stress voltage step where 50% or greater of the selected cloned non-supply pins
397 fail (see Annex A)

398 **3.36.**

399 **withstand voltage**

400 highest voltage level that does not cause device failure

401 Note 1 to entry: The device passes all tested lower voltages (see failure window).

402

403 **4. Apparatus and required equipment**

404 **4.1. Waveform verification equipment**

405 All equipment used to evaluate the tester shall be calibrated in accordance with the
406 manufacturer's recommendation. This includes the oscilloscope, current transducer and high
407 voltage resistor load. Maximum time between calibrations shall be one year. Calibration shall
408 be traceable to national or international standards.

409 Equipment capable of verifying the pulse waveforms defined in this standard test method
410 includes, but is not limited to, an oscilloscope, evaluation loads and a current transducer.

411 **4.2. Oscilloscope**

412 A digital oscilloscope is recommended but analogue oscilloscopes are also permitted. In order
413 to ensure accurate current waveform capture, the oscilloscope shall meet the following
414 requirements:

415 a) minimum sensitivity of 100 mA per major division when used in conjunction with the current
416 transducer specified in 4.4;

- 417 b) minimum bandwidth of 350 MHz;
 418 c) for analogue scopes, minimum writing rate of one major division per nanosecond.

419 **4.3. Additional requirements for digital oscilloscopes**

420 Where a digital oscilloscope is used, the following additional requirements apply:

- 421 a) recommended channels: 2 or more;
 422 b) minimum sampling rate: 10^9 samples per second;
 423 c) minimum vertical resolution: 8-bit;
 424 d) minimum vertical accuracy: $\pm 2,5$ %;
 425 e) minimum time base accuracy: 0,01 %;
 426 f) minimum record length: 10^3 points.

427 **4.4. Current probe**

- 428 a) minimum bandwidth of 200 MHz;
 429 b) peak pulse capability of 12 A;
 430 c) rise time of less than 1 ns;
 431 d) capable of accepting a solid conductor as specified in 4.5;
 432 e) provides an output voltage per signal current as required in 4.2
 433 (this is usually between 1 mV/mA and 5 mV/mA.);
 434 f) low-frequency 3 dB point below 10 kHz (e.g., Tektronix CT-2¹) for measurement of decay
 435 constant t_d (see 5.2.3.2, Table 1, and note below).

436 NOTE Results using a current probe with a low-frequency 3 dB point of 25 kHz (e.g., Tektronix CT-1¹) to
 437 measure decay constant t_d are acceptable if t_d is found to be between 130 ns and 165 ns.

438 **4.5. Evaluation loads**

439 Two evaluation loads are necessary to verify the tester functionality:

- 440 a) Load 1: A solid 18 AWG to 24 AWG (non-US standard wire size 0,25 mm² to 0,75 mm²
 441 cross-section) tinned copper shorting wire as short as practicable to span the distance
 442 between the two farthest pins in the socket while passing through the current probe or long
 443 enough to pass through the current probe and contacted by the probes of the non-socketed
 444 tester.
 445 b) Load 2: A $(500 \pm 5) \Omega$, minimum 4 000 V voltage rating.

446 **4.6. Attenuator**

447 A 20.0 dB attenuator with a precision of ± 0.5 dB, at least 1 GHz bandwidth, and an impedance
 448 of $50 \Omega \pm 5 \Omega$.

449 **4.7. Human body model simulator**

450 A simplified schematic of the HBM simulator or tester is given in Figure 1. The performance of
 451 the tester is influenced by parasitic capacitance and inductance. Thus, construction of a tester
 452 using this schematic does not guarantee that it will provide the HBM pulse required for this

¹ Tektronix CT-1 and CT-2 are the trade names of products supplied by Tektronix, Inc.

This information is given for the convenience of users of this document and does not constitute an endorsement by IEC of the products named. Equivalent products may be used if they can be shown to lead to the same results.